



PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANTS: Hyun HUH et al. CONF. NO.: 2580  
SERIAL NO.: 10/647,297 GROUP: 1771  
FILED: August 26, 2003 EXAMINER: Hai Vo  
FOR: Polishing Pad Containing Embedded Liquid Microelements and Method  
of Manufacturing the Same  
DOCKET NO.: 47881-000003/US

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Customer Service Window  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314  
**Mail Stop Amendment**

February 10, 2006

**RESPONSE TO RESTRICTION REQUIREMENT**

Dear Sir:

Responsive to the Examiner's Restriction Requirement dated December 12, 2005, the period for response having been extended one (1) month to February 12, 2006, the following remarks are respectfully submitted in connection with the above-referenced application.

**REMARKS**

Claims 1-16 remain in the present application.

**Election/Restriction Requirement**

The Examiner has imposed a Restriction Requirement, and requested that Applicants elect one of two identified groups of claims for prosecution in connection with the present application. The two groups of claims are as follows:

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